

KLA - Alpha-Step IQ Profilometer - Cleanroom

Overview

Contact profilometer, ideal for thin-film profilometry and measuring the step height of various materials during processing (e.g., etch depth).

LMACS Name	Alpha-Step IQ
Process Area	CHARACTERIZATION
Model	ASIQ
Vendor	KLA Instruments
Team	Breanna Cherkawski Gustavo de Oliveira Luiz Timothy Harrison Scott Munro Aaron Hryciw Adam Pettigrew

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System Features

Wafer Handling	pieces	100 mm	150 mm
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Key Documents

Wafer Handling	
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Related Documents

- [KLA - Alpha-Step IQ Profilometer - Characterization \(Equipment\)](#)
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 - [asiq](#)
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